

INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)	Docket Number (Optional) TWI-14120	Application Number <del>NEW</del> 10/733,598
	Applicant(s) Jon Opsal et al.	
	Filing Date HEREWITH	Group Art Unit Unknown 2857

#### U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
<i>hw</i>	*AA	4,999,014	03/12/1991	Gold et al.	356	382	05/04/1989
<i>hw</i>	*AB	5,042,951	08/27/1991	Gold et al.	356	369	09/19/1989
<i>hw</i>	*AC	5,181,080	01/19/1993	Fanton et al.	356	381	12/23/1991
<i>hw</i>	*AD	5,357,632	10/18/1994	Pian et al.	709	105	08/08/1991
<i>hw</i>	*AE	5,412,473	05/02/1995	Rosencwaig et al.	356	351	07/16/1993
<i>hw</i>	*AF	5,596,411	01/21/1997	Fanton et al.	356	369	03/18/1996
<i>hw</i>	*AG	5,607,800	03/04/1997	Ziger	430	8	02/15/1995
<i>hw</i>	*AH	5,608,526	03/04/1997	Piwonka-Corle et al.	356	369	01/19/1995
<i>hw</i>	*AI	5,739,909	04/14/1998	Blayo et al.	356	369	10/10/1995
<i>hw</i>	*AJ	5,867,276	02/02/1999	McNeil et al.	356	445	03/07/1997
<i>hw</i>	*AK	5,889,593	03/30/1999	Bareket	356	445	02/26/1997
<i>hw</i>	*AM	5,963,329	10/05/1999	Conrad et al.	356	372	10/31/1997
<i>hw</i>	*AN	5,933,794	08/03/1999	Stalzer	702	123	02/25/1997
<i>hw</i>	*AO	6,256,097	07/03/2001	Wagner	356	369	01/07/2000
<i>hw</i>	*AP	6,429,943	08/06/2002	Opsal et al.	356	625	03/27/2001
<i>hw</i>	*AQ	6,465,265	10/15/2002	Opsal et al.	438	16	03/13/2001
<i>hw</i>	*AR	6,483,580	11/19/2002	Xu et al.	356	300	03/06/1998

#### FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
<i>hw</i>	*AS	WO 99/02970	01/21/1999	PCT	G01N	21/21		
<i>hw</i>	*AT	WO 99/45340	09/10/1999	PCT	G01B	11/02		
<i>hw</i>	*AU	WO 02/23231 A2	03/21/2002	PCT	G02B	5/00		

#### OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

<i>hw</i>	*AV	U.S. Patent Application No. 09/818,703, filed March 27, 2001, entitled "Critical Dimension Analysis with Simultaneous Multiple Angle of Incidence Measurements," by Jon Opsal et al., 26 pages of specification and 2 sheets of informal drawings.
<i>hw</i>	*AW	"Why create libraries? Now you can perform in real-time" advertisement, Therna-Wave, one page, no date.
<i>hw</i>	*AX	Opsal et al., "Fundamental solutions for real-time optical CD metrology," <i>Metrology, Inspection, and Process Control for Microlithography XVI, Proceedings of SPIE</i> , Vol. 4689 (2002), 4-7 March 2002, pp. 163-176.

Examiner <i>Kelley</i>	Date Considered 2-6-02
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	